

## **“Application of thin-films to MEMS”**

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In this talk, we introduce the application of large area, low temperature thin-film silicon technology to microelectromechanical systems. The low-T fabrication of micromechanical structures such as microbridges and cantilevers, both on glass and plastic substrates, is described. The behavior of electrostatic actuators in the quasi-DC Regime and in resonance, both in vacuum and in dissipative media such as air and water, is described in detail. Finally, the fabrication of all-polymer MEMS structures and their electromechanical properties is introduced.